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PATENT

Case Docket No. ASMEX.282A

Date: October 1, 2001

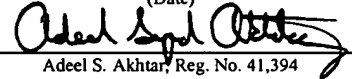
## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s) : Zhimin Lu  
Appl. No. : 09/870,393  
Filed : May 29, 2001  
For : METHOD AND  
APPARATUS TO CORRECT  
WAFER DRIFT  
Examiner : Unknown  
Group Art Unit : Unknown

I hereby certify that this correspondence and all  
marked attachments are being deposited with the  
United States Postal Service as first class mail in  
an envelope addressed to: Assistant Commissioner  
for Patents, Washington, D.C. 20231, on

October 1, 2001

(Date)

  
Adeel S. Akhtar, Reg. No. 41,394

## TRANSMITTAL LETTER

ASSISTANT COMMISSIONER FOR PATENTS  
WASHINGTON, D.C. 20231  
ATTENTION: APPLICATION BRANCH

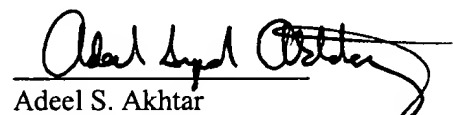
Dear Sir:

Enclosed for filing in the above-identified application are the following:

- (X) An Information Disclosure Statement;
- (X) A PTO Form 1449 with fifty-nine (59) references;

The Commissioner is hereby authorized to charge any additional fees which may be required, or credit  
any overpayment, to Account No. 11-1410; and

- (X) A return prepaid postcard.

  
Adeel S. Akhtar  
Registration No. 41,394  
Attorney of Record



## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant	:	Zhimin Lu	)	Group Art Unit Unknown
			)	
App. No.	:	09/870,393	)	
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Filed	:	May 29, 2001	)	
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For	:	METHOD AND	)	
		APPARATUS TO CORRECT	)	
		WAFER DRIFT	)	
			)	
Examiner	:	Unknown	)	
			)	

INFORMATION DISCLOSURE STATEMENT

Assistant Commissioner for Patents  
Washington, D.C. 20231

Dear Sir:

Enclosed is form PTO-1449 listing references that are also enclosed. This Information Disclosure Statement is being filed before the receipt of a first Office Action on the merits, and presumably no fee is required in accordance with 37 C.F.R. § 1.97(b)(3). If a first Office Action on the merits was mailed before the mailing date of this Statement, the Commissioner is authorized to charge the fee set forth in 37 C.F.R. § 1.17(p) to Deposit Account No. 11-1410.

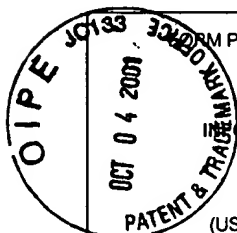
Respectfully submitted,

KNOBBE, MARTENS, OLSON & BEAR, LLP

Dated: October 1, 2001

By: Adeel S. Akhtar

Adeel S. Akhtar  
Registration No. 41,394  
Attorney of Record  
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Sixteenth Floor  
Newport Beach, CA 92660  
(415) 954-4114



FORM PTO-1449

U.S. DEPARTMENT OF COMMERCE  
PATENT AND TRADEMARK OFFICEATTY. DOCKET NO.  
ASMEX.282AAPPLICATION NO.  
09/870,393INFORMATION DISCLOSURE STATEMENT  
BY APPLICANT

(USE SEVERAL SHEETS IF NECESSARY)

APPLICANT  
Zhmin LuFILING DATE  
May 29, 2001GROUP  
Unknown

## U.S. PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE (IF APPROPRIATE)
	1	3,907,439	09/23/75	Zanoni			
	2	3,945,505	03/23/76	Frisbie et al.			
	3	4,024,944	05/24/77	Adams et al.			
	4	4,148,344	04/10/79	Critchell et al.			
	5	4,201,378	05/6/80	Hams			
	6	4,228,886	10/21/80	Moran			
	7	4,449,885	05/22/84	Hertel et al.			
	8	4,457,664	07/3/84	Judell et al.			
	9	4,466,073	08/14/84	Boyan et al.			
	10	4,507,078	03/26/85	Tam et al.			
	11	4,523,985	06/18/85	Dimock			
	12	4,559,451	12/17/85	Curl			
	13	4,635,373	01/13/87	Miyazaki et al.			
	14	4,647,266	03/3/87	Turner et al.			
	15	4,698,511	10/6/87	Sueda et al.			
	16	4,705,951	11/10/87	Layman et al.			
	17	4,720,635	1/19/88	Uga			
	18	4,744,713	05/17/88	Hrovath			
	19	4,765,793	08/23/88	Goddeau			
	20	4,770,590	09/13/88	Hugues et al.			
	21	4,789,294	12/6/88	Sato et al.			
	22	4,818,169	04/4/89	Schram, deceased et al.			
	23	4,819,167	04/4/89	Cheng et al.			
	24	4,833,790	05/30/89	Spencer et al.			
	25	4,836,733	06/6/89	Hortel et al.			
	26	4,880,348	11/14/89	Baker et al.			

EXAMINER

DATE CONSIDERED

\*EXAMINER: INITIAL IF CITATION CONSIDERED, WHETHER OR NOT CITATION IS IN CONFORMANCE WITH MPEP 609; DRAW LINE THROUGH CITATION IF NOT IN CONFORMANCE AND NOT CONSIDERED, INCLUDE COPY OF THIS FORM WITH NEXT COMMUNICATION TO APPLICANT.

FORM PTO-1449

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Unknown

## U.S. PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE (IF APPROPRIATE)
	27	4,907,035	03/6/90	Galburt et al.			
	28	5,044,752	09/3/91	Thurfjell et al.			
	29	5,162,642	11/10/92	Akamatsu et al.			
	30	5,194,743	03/16/93	Aoyama et al.			
	31	5,239,182	08/24/93	Tateyama et al.			
	32	5,483,138	01/09/96	Shmookler et al.			
	33	5,706,201	01/06/98	Andrews			
	34	5,706,930	01/13/98	Sahoda et al.			
	35	5,740,062	04/14/98	Berken et al.			
	36	5,768,125	06/16/98	Zinger et al.			
	37	5,822,213	10/13/98	Huynh			
	38	5,870,488	02/09/99	Rush et al.			
	39	5,905,850	05/18/99	Kaveh			
	40	5,917,601	06/29/99	Shimakzki et al.			
	41	5,980,194	11/09/99	Freerks et al.			
	42	US 6,198,976 B1	03/6/01	Sundar et al.			3/4/98

## FOREIGN PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
							YES	NO
	1	JP 58-055270	04/01/83	Japan			Abstract	
	2	JP 61-087352	05/02/86	Japan			Abstract	
	3	JP 61-184842	08/18/86	Japan			Abstract	
	4	JP 61-228639	10/11/86	Japan			Abstract	
	5	JP 62-073643	04/04/87	Japan			Abstract	

EXAMINER INITIAL	OTHER DOCUMENTS (INCLUDING AUTHOR, TITLE, DATE, PERTINENT PAGES, ETC.)	
	1	Sugimoto, S. et al., "Wafer loading and unloading robot," <u>Sharp Technical Journal</u> , No. 30, (1984), pp. 79-83.

EXAMINER	DATE CONSIDERED
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EXAMINER INITIAL	OTHER DOCUMENTS (INCLUDING AUTHOR, TITLE, DATE, PERTINENT PAGES, ETC.)	
	2	Kurt Petersen et al., "High-Performance Mass-Flow Sensor with Integrated Laminar Flow Micro-Channels," <u>International Conference on Solid State Sensors and Actuators - Digest of Technical Papers</u> (1985), pp. 361-363.
	3	GCA Corporation, (Wafertac1006 Advertisement), <u>Solid State Technology</u> , Vol. 28, No. 1, (Jan. 1985), p. 3.
	4	Brooks Automation, (Wafer Handling Robot), <u>Solid State Technology</u> , Vol. 28, No. 1, (Jan. 1985), p. 74.
	5	Zbigniew M. Wojcik, "A Method of Automatic Centering of Chips, Masks and Semiconductor Wafers," <u>Electron Technology</u> , (1977), Vol. 10, No. 3, pp. 79-96.
	6	IBM Technical Disclosure Bulletin, "Automatic Mask/Wafer Alignment System," (Sept. 1985), Vol. 28, No. 4, pp. 1474-1479.
	7	IBM Technical Disclosure Bulletin, "Vacuum-Compatible Low Contamination Wafer-Orientor System," (Feb. 1986), Vol. 28, No. 9, pp. 4056-4058.
	8	IBM Technical Disclosure Bulletin, "No-Edge Contact Wafer Orientor," (Jan. 1975), Vol. 17, No. 8, pp. 2220-2221.
	9	IBM Technical Disclosure Bulletin, "Front Wafer Registration Device for Batch Process Etch End-Pint Detection System," (Oct. 1977), Vol. 20, No. 5, pp. 1756-1759.
	10	Kimiyoshi Deguchi et al., "Alignment Accuracy Evaluation of X-Ray Lithography System SR-1," <u>Journal of the Japan Society of Precision Engineering</u> , (1985), Vol. 51, No. 5, pp. 156-162.
	11	ASM Europe, (Advance 400 Course Module 19), Rev. C, (June 1999)
	12	Keyence Corporation Brochure, "Laser Thru-beam Photoelectric Sensors LX2 Series," (date unknown)

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